

Practitioner's Docket No.: **MUH-12818****BOX AF**CERTIFICATION OF MAILING OR TRANSMISSION

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Laurence A. GreenbergDecember 11, 2006
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DEC 11 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/675,049 Confirmation No. 5871
Filing Date : September 30, 2003
Applicant : Ioannis Dotsikas
Title : Method and Furnace for the Vapor Phase
Deposition of Components onto
Semiconductor Substrates with a Variable
Main Flow Direction of the Process Gas
TC/AU : 2818
Examiner : Dung A. Le
Customer No. : 24131

A M E N D M E N T under 37 CFR. § 1.116

Mail Stop **BOX AF** Amendment
Hon. Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

S i r :

Responsive to the Office action dated August 11, 2006, kindly
amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of
claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.